

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claim 1 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support; and

wherein said RF bias generator has a bias frequency that is sufficiently low for ions in a plasma sheath near said workpiece to follow electric field oscillations across said sheath at said bias frequency.

Claim 2 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising

the species to be implanted in said layer of said workpiece;
generating from said process gas a plasma by
capacitively coupling RF source power across said workpiece
support and said ceiling or said sidewall from an RF source power
generator;

applying an RF bias from an RF bias generator to said
workpiece support; and

The method of Claim 1 wherein said RF bias generator has a bias frequency that is sufficiently low for ions in a plasma sheath near said workpiece to attain an ion energy at least nearly equivalent to a peak-to-peak voltage of said RF bias generator.

Claim 3 (previously presented): The method of Claim 2 wherein said bias frequency is sufficiently high so that RF voltage drops across dielectric layers on said workpiece do not exceed a predetermined fraction of an RF bias voltage applied to said workpiece support by said RF bias generator.

Claim 4 (original): The method of Claim 3 wherein said predetermined fraction corresponds to about 10%.

Claim 5 (previously presented): The method of Claim 1 further comprising setting said RF bias to a level corresponding to a desired depth in said layer to which said element is to be implanted.

Claim 6 (currently amended): A method for implanting ions
in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a
chamber with said layer being in facing relationship with a
ceiling of said chamber, thereby defining a processing zone
between said workpiece and said ceiling;

introducing into said chamber a process gas comprising
the species to be implanted in said layer of said workpiece;
generating from said process gas a plasma by
capacitively coupling RF source power across said workpiece
support and said ceiling or said sidewall from an RF source power
generator;

applying an RF bias from an RF bias generator to said
workpiece support;

setting said RF bias to a level corresponding to a
desired depth in said layer to which said element is to be
implanted; and

~~The method of Claim 5 wherein said layer comprises a semiconductor material, and said species to be implanted comprises a dopant impurity that promotes one of a p-type or n-type conductivity in said semiconductor material, and wherein said desired depth to which said element is to be implanted corresponds to a desired p-n junction depth.~~

Claim 7 (original): The method of Claim 6 wherein said gas comprises a chemical combination of said dopant impurity and another element.

Claim 8 (original): The method of Claim 7 wherein said gas comprises a fluoride of said dopant impurity.

Claim 9 (original): The method of Claim 7 wherein said gas comprises a hydride of said dopant impurity.

Claim 10 (previously presented): The method of Claim 7 wherein said gas further comprises a co-implant ion bombardment element which removes from a top surface of said layer a material that tends to accumulate during implantation of said dopant impurity.

Claim 11 (previously presented): The method of Claim 1 wherein said layer comprises a semiconductor crystal which is to be implanted with a dopant impurity element, and wherein said species comprises a pre-implant ion bombardment species that creates damage in said semiconductor crystal for amorphizing said layer.

Claim 12 (previously presented): The method of Claim 1 wherein said layer comprises a dielectric thin film, and wherein said species comprises a surface-enhancement species which enhances a characteristic of said dielectric thin film layer upon implantation and substitution.

Claim 13 (original): The method of Claim 12 wherein said characteristic is the electrical behavior of said dielectric thin film.

Claim 14 (original): The method of Claim 12 wherein said dielectric thin film comprises an oxide of a semiconductor element, and said species comprises a non-oxygen element to be substituted for oxygen atoms in said dielectric thin film.

Claim 15 (original): The method of Claim 1 wherein the step of placing said workpiece on said workpiece support is preceded by:

introducing a passivation process gas containing passivation-forming chemical species;

forming a passivation layer on interior surfaces of said chamber by generating from said passivation gas a plasma in said processing zone.

Claim 16 (original): The method of Claim 15 wherein said

passivation gas comprises one of a hydride, a fluoride or an oxide of a semiconductor element.

Claim 17 (original): The method of Claim 16 wherein said passivation gas comprises a chemical species containing carbon and fluorine.

Claim 18 (original): The method of Claim 15 wherein the step of generating a plasma from said process gas is followed by:
removing said process gas from said chamber;
removing said workpiece from said chamber;
introducing a passivation layer-removing gas into said chamber;
generating from said passivation layer-removing gas, a plasma in said processing zone, so as to remove said passivation layer from said interior surfaces of said chamber.

Claim 19 (original): The method of Claim 18 further comprising heating said interior surfaces of said chamber during the removal of said passivation layer.

Claim 20 (original): The method of Claim 18 wherein said passivation layer-removing gas comprises a fluorine-containing gas.

Claim 21 (original): The method of Claim 18 wherein said passivation layer-removing gas comprises a hydrogen-containing gas.

Claim 22 (original): The method of Claim 1 wherein the step of introducing said process gas is preceded by:
pre-cleaning said wafer.

Claim 23 (original): The method of Claim 22 wherein the step of precleaning said wafer comprises removing an accumulated layer therefrom.

Claim 24 (original): The method of Claim 23 wherein the step of removing comprises removing an oxide layer from said workpiece.

Claim 25 (original): The method of Claim 24 wherein the step of removing an oxide layer comprises etching said oxide layer.

Claim 26 (previously presented): The method of Claim 1 wherein the step of generating a plasma from said process gas is followed by:

heating said layer of said workpiece to an anneal temperature sufficiently high to cause atoms of the species implanted in said layer to be substituted into atomic sites in a crystal lattice of said layer.

Claim 27 (previously presented): The method of Claim 26 wherein said layer is masked by a photolithographic layer defining a pattern of ion implantation, and wherein the step of heating said surface is preceded by:

removing said photolithographic layer.

Claim 28 (original): The method of Claim 27 wherein the step of removing said photolithographic layer is carried out in a pyrolyzation chamber.

Claim 29 (previously presented): The method of Claim 26 wherein the step of heating said layer is carried out after removing said workpiece from said chamber and placing it in an

anneal chamber.

Claim 30 (original): The method of Claim 6 wherein said process gas is one of (a) hydride of said dopant species or (b) a fluoride of said dopant species, and said ion bombardment element comprises one of: Helium, Hydrogen, a semiconductor element of the type including Silicon, Germanium, Carbon, a fluoride of a semiconductor element of the type including fluorides of Silicon, Germanium, Carbon.

Claim 31 (original): The method of Claim 18 wherein said passivation layer-removing gas comprises NF3.

Claim 32 (original): The method of Claim 6 wherein said semiconductor material is silicon and said dopant impurity is boron.

Claim 33 (original): The method of Claim 6 wherein said semiconductor element is silicon and said dopant impurity is phosphorus.

Claim 34 (original): The method of Claim 6 wherein said semiconductor element is silicon and said dopant impurity is arsenic.

Claim 35 (original): The method of Claim 14 wherein said semiconductor element comprises one of silicon or germanium.

Claim 36 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone

between said workpiece and said ceiling;
introducing into said chamber a process gas comprising
the species to be implanted in said layer of said workpiece;
generating from said process gas a plasma by
capacitively coupling RF source power across said workpiece
support and said ceiling or said sidewall from an RF source power
generator;

applying an RF bias from an RF bias generator to said
workpiece support;

~~The method of Claim 1 wherein[[:]] said layer comprises~~
plural dielectric gates formed over an underlying layer having
horizontal and non-horizontal surfaces; and

the step of applying bias power comprises selecting a
level of said bias power promotive of a sufficiently collisional
plasma sheath over said workpiece to produce a significant
fraction of ions impacting said layer at trajectories other than
orthogonal to said layer whereby to implant ions in said
horizontal and non-horizontal surfaces of said layer.

Claim 37 (previously presented): The method of Claim 6
wherein said layer comprises a crystal lattice and wherein the
step of generating a plasma from said process gas is preceded by:

introducing into said chamber an amorphizing gas
comprising an ion bombardment species;

generating from said amorphizing gas a plasma in said
processing zone;

applying bias power to said workpiece support to
attract ions of said ion bombardment species from said plasma
toward said layer whereby said ions cause damage in said crystal
lattice to amorphize said crystal lattice.

Claim 38 (original): The method of Claim 37 wherein said
ion bombardment species comprises a semiconductive species.

Claim 39 (original): The method of Claim 38 wherein said ion bombardment species comprises one of silicon or germanium.

Claim 40 (previously presented): The method of Claim 7 wherein said process gas further comprises an ion bombardment species for co-implantation with said dopant impurity in said surface layer.

Claim 41 (previously presented): The method of Claim 40 wherein ions of said ion bombardment species are implanted in said layer to cause crystal lattice damage for amorphizing said layer during implantation of said dopant impurity in said layer.

Claim 42 (original): The method of Claim 41 wherein said ion bombardment species comprises a semiconductor species.

Claim 43 (original): The method of Claim 42 wherein said semiconductor species comprises one of silicon or germanium.

Claim 44 (original): The method of Claim 1 wherein said bias comprises RF power.

Claim 45 (original): The method of Claim 44 further comprising pulse modulating said RF bias power.

Claim 46 (original): The method of Claim 45 further comprising pulse modulating said RF source power.

Claim 47 (original): The method of Claim 46 further comprising maintaining a relation between the pulse modulating of said RF bias power and the pulse modulating of said RF source power that is one of:

- (a) push-pull;
- (b) in-synchronism;
- (c) symmetrical;
- (d) non-symmetrical.

Claim 48 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support; and

~~The method of Claim 1 wherein the step of applying said bias power comprises applying a single burst of said bias power to said workpiece support.~~

Claim 49 (original): The method of Claim 48 wherein said single burst has a duration corresponding to a desired implant dosage.

Claim 50 (original): The method of Claim 49 further comprising:

sensing when a voltage measured near said workpiece support reaches a threshold corresponding to the desired implant depth in response to applying said bias power;

triggering a clock in response to said sensing step,

and terminating said bias power when said clock reaches said duration.

Claim 51 (previously presented): The method of Claim 50 further comprising controlling said bias power so as to produce a bias voltage near said workpiece support at least nearly equal to said threshold.

Claim 52 (canceled)

Claim 53 (currently amended): The method of Claim 1 [52] wherein said bias frequency is sufficiently high so that RF voltage drops across dielectric layers on said workpiece do not exceed a predetermined fraction of an RF bias voltage of said RF bias generator.

Claim 54 (original): The method of Claim 53 wherein said predetermined fraction corresponds to about 10%.

Claim 55 (original): The method of Claim 1 wherein said RF bias generator has a bias frequency between 10 kHz and 10 MHz.

Claim 56 (original): The method of Claim 1 wherein said RF bias generator has a bias frequency between 50 kHz and 5 MHz.

Claim 57 (original): The method of Claim 1 wherein said RF bias generator has a bias frequency between 100 kHz and 3 MHz.

Claim 58 (original): The method of Claim 1 wherein said RF bias generator has a bias frequency of about 2 MHz to within about 5%.

Claim 59 (currently amended): A method for implanting ions

in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support; and

The method of Claim 1 wherein said species to be implanted comprises a first atomic element, said process gas further comprising:

a second atomic element in chemical combination with said first atomic element.

Claim 60 (previously presented): The method of Claim 59 wherein said layer of said workpiece is a semiconductor material and said first atomic element is an n-type or p-type conductivity dopant impurity with respect to said semiconductor material.

Claim 61 (original): The method of Claim 60 wherein said second atomic element comprises a semiconductor element.

Claim 62 (previously presented): The method of Claim 61 wherein said second atomic element and said semiconductor material of said layer are the same atomic element.

Claim 63 (previously presented): The method of Claim 60 wherein said second atomic element is an element having a greater

tendency than said first atomic element following ion implantation to diffuse out of said layer upon heating of said layer.

Claim 64 (original): The method of Claim 60 wherein said second atomic element comprises one of hydrogen and fluorine.

Claim 65 (original): The method of Claim 60 wherein the chemical combination of said first and second atomic species comprises a first molecular species, said process gas further comprising a second molecular species.

Claim 66 (original): The method of Claim 65 wherein said second molecular species comprises one of: (a) hydrogen gas, (b) fluorine-containing gas.

Claim 67 (original): The method of Claim 64 wherein said first molecular species comprises a fluoride of said dopant impurity and said second molecular species comprises a hydride of said dopant impurity.

Claim 68 (original): The method of Claim 67 wherein said process gas further comprises a third molecular species.

Claim 69 (original): The method of Claim 68 wherein said third molecular species comprises at least one of (a) hydrogen-containing gas, (b) fluorine-containing gas, (c) an inert gas.

Claim 70 (original): The method of Claim 1 further comprising:

providing a cleaning plasma species source reactor;
prior to the step of introducing said workpiece,
producing a plasma in said cleaning species source reactor from

chamber cleaning species precursor gases to produce chamber cleaning plasma species;

furnishing said chamber cleaning plasma species from said cleaning species source reactor into said plasma immersion ion implantation reactor so as to clean interior surfaces of said plasma reactor, and then removing said chamber-cleaning plasma species from said plasma immersion ion implantation reactor.

Claim 71 (original): The method of Claim 70 wherein said chamber cleaning precursor gases comprise a fluorine-containing species and said chamber cleaning plasma species comprise fluorine-containing radicals.

Claim 72 (original): The method of claim 70 wherein said chamber cleaning precursor gases comprise a hydrogen-containing species and said chamber cleaning plasma species comprise hydrogen-containing radicals.

Claim 73 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support;

The method of Claim 1 further comprising:

providing an optical metrology chamber;
obtaining a measurement of ion implantation in a workpiece previously processed in said plasma immersion ion implantation reactor; and

adjusting said magnitude of said bias in accordance with said measurement.

Claim 74 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support;

~~The method of Claim 1 further comprising:~~

providing an ion beam implantation apparatus; and

placing said workpiece in said ion beam implantation apparatus and implanting a second species in said layer.

Claim 75 (previously presented): The method of Claim 74 wherein said layer is a semiconductor material, and said first and second species are dopant impurities of opposite conductivity types relative to said semiconductor material.

Claim 76 (previously presented): The method of Claim 75 further comprising:

masking devices on said workpiece of one conductivity type and exposing devices of an opposite conductivity type during ion implantation of said first species in said plasma immersion ion implantation reactor;

masking devices on said workpiece of said opposite conductivity type and exposing devices of the one conductivity type during ion implantation of said second species in said ion beam implantation apparatus.

Claim 77 (original): The method of Claim 76 wherein said first species is of a lower mass than said second species.

Claim 78 (original): The method of Claim 76 wherein said first species comprises boron and said second species comprises arsenic.

Claim 79 (previously presented): The method of Claim 1 further comprising:

providing an anneal chamber;

after the step of generating a plasma, removing said workpiece from said plasma immersion ion implantation reactor and placing it in said anneal chamber, and heating said layer sufficiently to cause at least some of the species ion implanted in said layer to be substituted into crystal lattice atomic sites of said layer.

Claim 80 (original): The method of Claim 79 wherein the step of heating comprises a dynamic surface anneal process.

Claim 81 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a

ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support;

~~The method of Claim 1 further comprising:~~

providing a photoresist strip chamber; and

the step generating a plasma is followed by placing said workpiece in said photoresist strip chamber and removing photoresist from said workpiece.

Claim 82 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support;

~~The method of Claim 1 further comprising:~~

providing a wet clean chamber; and

and wherein the step of generating said plasma is

followed by placing said workpiece in said wet clean chamber.

Claim 83 (currently amended): A method for implanting ions in a layer of a workpiece, comprising:

placing said workpiece on a workpiece support in a chamber with said layer being in facing relationship with a ceiling of said chamber, thereby defining a processing zone between said workpiece and said ceiling;

introducing into said chamber a process gas comprising the species to be implanted in said layer of said workpiece;

generating from said process gas a plasma by capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator;

applying an RF bias from an RF bias generator to said workpiece support;

~~The method of Claim 1 further comprising:~~

providing a second plasma immersion ion implantation reactor; and

placing said workpiece in said second plasma immersion ion implantation reactor and implanting a second species in said layer.

Claim 84 (previously presented): The method of Claim 83 wherein said layer is a semiconductor material, and said first and second species are dopant impurities of opposite conductivity types relative to said semiconductor material.

Claim 85 (original): The method of Claim 84 further comprising:

masking devices on said workpiece of one conductivity type and exposing devices of an opposite conductivity type during ion implantation of said first species in said plasma immersion

ion implantation reactor;

masking devices on said workpiece of said opposite conductivity type and exposing devices of the one conductivity type during ion implantation of said second species in said second plasma immersion ion implantation reactor.

Claim 86 (original): The method of Claim 1 wherein the step of capacitively coupling RF source power across said workpiece support and said ceiling or sidewall from an RF source power generator comprises applying RF power from said RF source power generator to said ceiling or said sidewall while connecting said workpiece support pedestal to an RF return potential.

Claim 87 (original): The method of Claim 1 wherein the step of capacitively coupling RF source power across said workpiece support and said ceiling or said sidewall from an RF source power generator comprises applying RF power from said RF source power generator to said workpiece support pedestal while connecting said ceiling or said sidewall to an RF return potential.